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MEMC 98-4650 (2293)
PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of Gregory Wilson, et al.

Serial No. 09/608,302

Filed June 30, 2000

Confirmation No. 9819

For A METHOD AND APPARATUS FOR FORMING A SILICON WAFER WITH A
DENUDED ZONE

January 14, 2002

TO THE COMMISSIONER OF PATENTS AND TRADEMARKS,

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SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

* In accordance with 37 C.F.R. 1.97 and 1.98 and MPEP 609, and in compliance with the duty of disclosure set forth in 37 C.F.R. 1.56, applicants submit copies of the references listed on the attached PTO/SB/08A for consideration by the Patent and Trademark Office in the above-entitled application and to be made of record therein.

I certify that each item contained in this statement was first cited in a communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this statement.

Respectfully submitted,

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